

Examiner-Initiated Interview Summary	Application No. 09/825,664	Applicant(s) HEMBREE, DAVID R.	
	Examiner VINH P NGUYEN	Art Unit 2829	

All Participants:

(1) VINH P NGUYEN.

(2) Mr. Shaurette.

Status of Application: _____

(3) _____.

(4) _____.

Date of Interview: 12 March 2004

Time: _____

Type of Interview:

- ☒ Telephonic
☐ Video Conference
☐ Personal (Copy given to: ☐ Applicant ☐ Applicant's representative)

Exhibit Shown or Demonstrated: ☐ Yes ☐ No

If Yes, provide a brief description: _____

Part I.

Rejection(s) discussed:

n/a

Claims discussed:

62,70-73,75-78

Prior art documents discussed:

n/a

Part II.

SUBSTANCE OF INTERVIEW DESCRIBING THE GENERAL NATURE OF WHAT WAS DISCUSSED:

Examiner discussed with Mr. Shaurette about making some changes in claims 62,70-73 and 75-78 for improving the clarity (see Examiner's amendment)

Part III.

- ☒ It is not necessary for applicant to provide a separate record of the substance of the interview, since the interview directly resulted in the allowance of the application. The examiner will provide a written summary of the substance of the interview in the Notice of Allowability.
☐ It is not necessary for applicant to provide a separate record of the substance of the interview, since the interview did not result in resolution of all issues. A brief summary by the examiner appears in Part II above.

(Examiner/SPE Signature)

(Applicant/Applicant's Representative Signature – if appropriate)

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

In claim 62, line 2, -- an-- has been changed to -- the --.

In claim 70, -- environment within the wafer processing apparatus to form a plurality of discrete integrated circuits of a plurality of respective dies to be singulated from the wafer at a subsequent moment in time.-- has been changed to --environment. --.

In claim 71, lines 3-4, --member to fabricate a plurality of discrete integrated circuits of a plurality of respective dies to be singulated from the wafer at a subsequent moment in time. -- has been changed to --member. --.

In claim 72, lines 3-4, --member to fabricate a plurality of discrete integrated circuits of a plurality of respective dies to be singulated from the wafer at a subsequent moment in time. -- has been changed to --member. --.

In claim 75, line 3-4, -- apparatus to form a plurality of discrete integrated circuits of a plurality of respective dies to be singulated from the wafer at a subsequent moment in time. -- has been changed to --apparatus. --.


In claim 76, lines 3-4, -- apparatus to form a plurality of discrete integrated circuits of a plurality of respective dies to be singulated from the wafer at a subsequent moment in time. -- has been changed to --apparatus. --.

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In claim 77, lines 3-4, --member to fabricate a plurality of discrete integrated circuits of a plurality of respective dies to be singulated from the wafer at a subsequent moment in time. -- has been changed to --member. --.

In claim 78, lines 3-4, --member to fabricate a plurality of discrete integrated circuits of a plurality of respective dies to be singulated from the wafer at a subsequent moment in time. -- has been changed to --member. --.

2. Authorization for this examiner's amendment was given in a telephone interview with Mr. Shaurette on 03/12/04.


VINH P. NGUYEN
PRIMARY EXAMINER
ART UNIT 2829
03/12/04